

PCT-150RE TRACK SYSTEM
(MASS PRODUCTION WITH 2 TRACKS, LIFT-OFF TOOL SET)

Please contact Sales sales@picotrack.com for more information



Track System Specification	Description
System designed	US Standard System
System Configuration	TRACK 2: SEND - LOF 1 - LOF 2 - REC TRACK 1: SEND - LOF 1 - LOF 2 - REC
System dimension	87.5" length x 40" width x 90" height
Wafer size	Up to 6" (150mm)
Wafer Sensor	Capacity or Optical
Wafer material	Silicon/Sapphire/GaAs/ Ceramic...
System Controller	PC & PLC Controller with Windows OS based
Chemical canister cabinet	Solvents (IPA, ACE, Cleaning liquid...), D.I.Water
Indexer wafer cassette capacity	4 Cassettes
Robot Arm Transfer Unit	6 Robot Arm
Forearm Arm type	Aluminium clear anodized
System Fan Filter Unit (FFU)	Optional
System Enclosure and windows	Optional
Photoresist temperature control	Optional ($\leq 1^{\circ}\text{C}$, 10-50 $^{\circ}\text{C}$ range)
High pressure liquid pump (HP)	Up to 5000 psi
LIFT- OFF Module	4 Modules
Catch sup set	SST
Spindle unit	Up/down motion
Maximum spin speed	6000 rpm
Spin motor	Servo
Spin speed accuracy	± 3 rpm
Acceleration range	0-50000 rpm/sec
Spin direction	Clockwise (+) & counter clockwise (-)
Dispense arm motion control	Stepper motor and driver
Dispense arm accuracy	± 0.1 mm
Wafer centering tolerance	± 0.1 mm
Dispense arm nozzles	Solvents top rinse and high pressure liquid with flowmeter control
Dispense type	Stream, puddle, fan spray, cone spray
Dispense method	Static, radial and sweep with pressurized canister and HP liquid pump
D1 water top and back side rinse	Yes
N2 Airing back side	Yes
N2 Blow-off side nozzle	Yes
Developer fluid temperature control	Optional $\leq 1^{\circ}\text{C}$ (10-50 $^{\circ}\text{C}$ range)
N2 Air Filter	0.2 μm
Solvents, D.I.Water Filter	0.1 μm